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Introduction

The document you hold in your hands is the Proceedings of the Optics and Measurement International Conference 2016, organized with the aim to provide an opportunity for experts from industrial and academic communities to share their experience and knowledge in the field of research and development of optical elements, systems, technological processes, and measuring methods.

Leading specialists from the whole of Europe were invited by the Institute of Plasma Physics of the CAS and its TOPTEC Research Centre to meet in Liberec, the Czech Republic, and discuss the above mentioned topics. Professional discussions were conducted in a very friendly atmosphere and accompanied by the official conference program as well as by informal meetings, which we believe you enjoyed.

We appreciate the attendance of experts in presented topics who prepared interesting invited lectures. Sven Kiontke, a respected authority on ultra-precise aspheric optics, engaged the attention of the audience by his presentation of the challenges in the manufacturing of highly precise lenses. The experience and results in the domain of tolerancing aspheric surfaces for optimized manufacturing of Ulrike Fuchs were also highly valued and we believe that many of the attendees were inspired by her talk to explore new technological procedures. Equally gripping was the lecture by Guido Gubbels, who introduced his team's results in the grinding and polishing of steep free-form lenses and pointed out some difficulties related to this promising field. Another perspective on R & D was introduced by Karel Blažek from CRYTUR Company, who presented the current problems of scientific results commercialization and technology transfer by way of examples from the scintillation area.

Special thanks belong to the organizations who decided to support the conference, especially to the general partner - asphericon GmbH from Germany, along with Crytur, spol. s r.o., Light Tec SARL, Mahr GmbH, Meopta – optika, s.r.o., and OptiXs, s.r.o.

Also, the Czech & Slovak Society for Photonics joined the conference this year by arranging the Best Czech & Slovak Student Paper Award. Congratulations to the winner Štěpán Kunc who attracted the jury's attention by his presentation titled Passive optical resonator for OSQAR LSW experiment.

We believe that the third Optics and Measurement International Conference was beneficial for all the attendees and that the meeting with colleagues from both academic and industrial organizations enabled them to establish new contacts and to gain new perspectives on current topics.

Jana Kovacicinova